

Form PTO-1449

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062020-1450Serial No.
10/669,178

INFORMATION DISCLOSURE CITATION

Applicant
Farrokh Ayazi, et al.Filing Date
09/23/2003

Group

JUN 25 2004

(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DT	A	5,839,062	11/17/98	Nguyen, et al.	455	323	03/18/94
DT	B	6,466,106 B1	10/15/02	Gamo	333	189	09/06/00
DT	C	6,563,402 B2	05/13/03	Kundu	333	202	05/30/01
DT	D	6,125,271	09/26/00	Rowland, Jr.	455	313	03/06/98
DT	E	2003/0129957 A1	07/10/03	Shingaki, et al.	455	307	12/23/02
DT	F	5,933,061	08/03/99	Takamoro, et al.	333	189	08/06/98
DT	G	6,628,177 B2	09/30/03	Clark, et al.	333	186	08/23/01
	H						
	I						
	J						
	K						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
DT	L	JP 63-232610 A	09/28/88	Japan	333	187	X	X
	M							
	N							
	O							

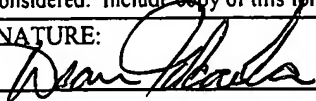
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

DT	P	International Search Report
	Q	
	R	

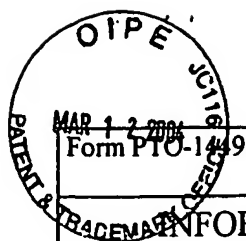
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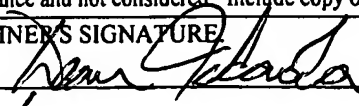
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MAR 12 2004 Form PTO-1449					Attorney Docket No. 62020-1450		Serial No. 10/669,178	
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U.S. PATENT DOCUMENTS								
Examiner Initials	Item	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DT	A	6,549,099	4-15-03	Taussig	333	186	6-29-01	
FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
DT	B	WO 02/01717 A1	1/3/02	PCT	H03H	9/46	Abstract	
DT	C	WO 03/043189 A2	5/22/03	PCT	H03H	9/24	Abstract	
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)								
DT	D	Galayko, D., Kaiser, A., Buchailot, L. et al. (2003) Microelectromechanical Variable-Bandwidth IF Frequency Filters With Tunable Electrostatic Coupling Spring. IEEE., pp. 153-156						
DT	E	No, S.Y., Hashimura, A., Pourkamali, S. et al., Single-Crystal Silicon HARPSS Capacitive Resonators with Submicron Gap-Spacing, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA; for proceedings at Hilton Head 2002.						
	F	Pourkamali, S., Abdolvand, R., Hashimura, A. et al. HARPSS Single Crystal Silicon Filter Arrays. School of Electrical and Computer Engineering, Georgia Institute of Technology, GA.						
DT	G	Wang, K., Bannon, F.D., Clark, J.R. et al. (1997) Q-Enhancement of Microelectromechanical Filters Via Low-Velocity Spring Coupling., Proceedings, IEEE International Ultrasonics Symposium, Toronto, Canada, Oct. 5-8, 1997, pp. 323-327.						
DT	H	Wang, K. and Nguyen, T.C. (1997) High-Order Micromechanical Electronic Filters, Proceedings, IEEE International Micro Electro Mechanical Systems Workshop, Nagoya, Japan, Jan. 26-30, 1997, pp. 25-30.						
DT	I	Pourkamali, et al. A 600kHz Electrically-Coupled MEMS Bandpass Filter, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA, MEMS 2003 Conference, Kyoto Japan, Jan. 19-23, 2003.						
DT	J	Pourkamali, et al. Electrostatically Coupled Micromechanical Beam Filters, School of Electrical and Computer Engineering, Georgia Institute of Technology, GA, MEMS 2003 Conference, Kyoto, Japan, Jan. 19-23, 2003, Pages 702-705.						
DT	K	Ayazi, Farrokh, et al., Capacitive Resonators And Methods Of Fabrication, filed with the USPTO on July 31, 2003, having serial no. 10/632,176.						
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